

## **LISTING OF THE CLAIMS**

This listing of claims will replace all prior versions, and listings, of claims in the application:

1. **(Currently Amended)** A substrate processing apparatus comprising:  
a substrate processing unit for performing a predetermined process on a substrate; and  
a substrate transfer unit for holding a container for storing substrates therein and  
transferring said substrates stored in said container to said substrate processing unit, wherein  
said substrate transfer unit includes:  
a mounting part for mounting said container thereon on a fixed shelf to transfer said  
substrates stored in said container to said substrate processing unit;  
a first shelf line containing a plurality of first shelves arranged in a vertical direction at a  
first predetermined interval, each being capable of mounting said container thereon;  
a second shelf line provided between said mounting part and said first shelf line and  
containing a plurality of second shelves arranged in the vertical direction at a second  
predetermined interval, each being capable of mounting said container thereon;  
a displacing element for displacing at least one of said plurality of second shelves  
corresponding to one of said plurality of first shelves in the vertical direction, wherein said one of  
said plurality of first shelves in said first shelf line, said displaced one of said plurality of first  
shelves holding holds a container to be transported, and said one of said plurality of second  
shelves holding a container to be transported, relative to the other in the vertical direction,  
thereby ensuring a container transport path of a height greater than said second predetermined  
interval in said second shelf line; and  
a transport element for transporting said container to be transported mounted on said  
displaced one of said plurality of first shelves to said shelf in mounting part in the horizontal  
direction along said container transport path created by said displacing element while holding  
said container.

2. **(Original)** The substrate processing apparatus according to claim 1, wherein said displacing element is connected to at least part of said plurality of second shelves for displacing said at least part of said plurality of second shelves in the vertical direction.

3. **(Original)** The substrate processing apparatus according to claim 2, wherein said displacing element includes a plurality of displacing mechanisms connected to said plurality of second shelves, respectively, each being capable of displacing a corresponding one of said plurality of second shelves individually in the vertical direction.

4. **(Original)** The substrate processing apparatus according to claim 3, wherein the number of shelves in said second shelf line is less than that of shelves in said first shelf line in the vertical direction, and  
displacement of said plurality of second shelves is performed by said displacing element within the height of said first shelf line in the vertical direction.

5. **(Original)** The substrate processing apparatus according to claim 4, wherein the number of shelves in said second shelf line is less by one than that of shelves in said first shelf line in the vertical direction, and  
the amount of displacement of each of said plurality of second shelves performed by said displacing element corresponds to said second predetermined interval.

6. **(Canceled)**